Ref #	Hits	Search Query	DBs ·	Default Operator	Plurals	Time Stamp
S1	762	(mirror or reflector) with curv\$ with (tilt\$6 or pivot\$6)	US-PGPUB; USPAT	OR	ON	2004/08/28 13:33
S2	345	S1 and ("385"/\$.ccls. or "359"/\$.ccls.)	US-PGPUB; USPAT	OR	ON	2004/08/28 13:34
S3	141	S2 and (layer\$6 or substrat\$6)	US-PGPUB; USPAT	OR	ON	2004/11/16 14:11
S4	1	"20030138213" and (actuat\$6 with layer)	US-PGPUB; USPAT	OR	ON	2004/11/29 11:25
S5	0	(MEM with dop\$6 with curv\$6) same mirror	USPAT	OR	ON	2004/01/09 10:39
S6	106	MEM with dop\$6	USPAT	OR	ON	2004/01/09 10:28
S7	18	(MEM with dop\$6) and (mirror or relect\$6)	USPAT	OR	ON	2003/09/12 15:23
S8	1	MEM with dop\$6 with curv\$6	USPAT	OR	ON	2003/09/12 15:23
S9	1	((MEMS or MOEMS) same (mirror\$4 or reflect\$7 or HR)) and ((mirror\$4 or reflect\$7 or HR) with (micrometer or ". mu."\$8)) and (curvature with radius)	USPAT	OR	ON	2004/01/08 11:41
S10	9	((MEMS or MOEMS) same (mirror\$4 or reflect\$7 or HR)) and ((mirror\$4 or reflect\$7 or HR) with (micrometer or ". mu."\$8)) and (curvature with radius)	US-PGPUB; USPAT	OR	ON	2004/08/28 13:30
S11		"20030138213"	US-PGPUB; USPAT	OR	ON	2004/01/08 11:51
S12	9	((MEMS or MOEMS) same (mirror\$4 or reflect\$7 or HR)) and ((mirror\$4 or reflect\$7 or HR) with (micrometer or ". mu.m")) and (curvature with radius)	US-PGPUB; USPAT	OR	ON	2004/01/08 12:56
S13	7	(((MEMS or MOEMS) same (mirror\$4 or reflect\$7 or HR)) and ((mirror\$4 or reflect\$7 or HR) with (micrometer or ". mu.m")) and (curvature with radius)) and "mu.m"	US-PGPUB; USPAT	OR	ON	2004/01/08 12:56
S14	7	(((MEMS or MOEMS) same (mirror\$4 or reflect\$7 or HR)) and ((mirror\$4 or reflect\$7 or HR) with (micrometer or ". mu.m")) and (curvature with radius)) and "mu.m"\$8	US-PGPUB; USPAT	OR	ON	2004/01/10 17:33
S15	1	"6525880".pn.	US-PGPUB; USPAT	OR	ON	2004/01/08 14:27
S16	2	(coat\$6 with layer\$6) and (MEMS or MOEMS) and ((process or method) with (mak\$6 orfabricat\$6 or manufactur\$6)) and (etch\$8 with layer\$6) and (dop\$6 with curv\$7)	USPAT	OR	ON	2004/01/09 10:14

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S17	5	(coat\$6 with layer\$6) and (MEMS or MOEMS) and ((process or method) with (mak\$6 orfabricat\$6 or manufactur\$6)) and (etch\$8 with layer\$6) and (dop\$6 with curv\$7)	US-PGPUB; USPAT	OR	ON	2004/01/09 10:15
S18	8	(coat\$6 with layer\$6) and (MEMS or MOEMS) and ((process or method) with (mak\$6 or fabricat\$6 or manufactur\$6)) and (etch\$8 with layer\$6) and (dop\$6 with curv\$7)	US-PGPUB; USPAT	OR	ON	2004/08/28 15:00
S19	1	((MEM or MOEM) with dop\$6) with ((curv\$6 or bend\$6) with (substrat\$6 or wafer\$6))	USPAT	OR	ON	2004/01/09 10:45
S20	510	(coat\$6 with layer\$6) and (MEMS or MOEMS) and ((process or method) with (mak\$6 or fabricat\$6 or manufactur\$6)) and (etch\$8 with layer\$6)	USPAT	OR	ON	2004/01/09 10:31
S21	1005	(coat\$6 with layer\$6) and (MEMS or MOEMS) and ((process or method) with (mak\$6 or fabricat\$6 or manufactur\$6)) and (etch\$8 with layer\$6)	US-PGPUB; USPAT	OR	ON	2004/01/09 10:45
S22	22	(MEMS or Moems) and (dop\$6 with curvature)	US-PGPUB; USPAT	OR	ON	2004/01/09 10:40
S23	161	(coat\$6 with layer\$6) and (MEMS or MOEMS) and ((process or method) with (mak\$6 or fabricat\$6 or manufactur\$6)) and (etch\$8 with layer\$6) and ((curv\$6 or bend\$6) with (substrat\$6 or wafer\$6))	US-PGPUB; USPAT	OR	ON	2004/01/09 11:07
S24	123	((coat\$6 with layer\$6) and (MEMS or MOEMS) and ((process or method) with (mak\$6 or fabricat\$6 or manufactur\$6)) and (etch\$8 with layer\$6) and ((curv\$6 or bend\$6) with (substrat\$6 or wafer\$6))) and (mirror\$4 or reflect\$8)	US-PGPUB; USPAT	OR	ON	2004/01/09 11:07
S25	51	((coat\$6 with layer\$6) and (MEMS or MOEMS) and ((process or method) with (mak\$6 or fabricat\$6 or manufactur\$6)) and (etch\$8 with layer\$6) and ((curv\$6 or bend\$6) with (substrat\$6 or wafer\$6))) and (mirror\$4 or reflect\$8) and (dop\$6 same substrate)	US-PGPUB; USPAT	OR	ON	2004/01/09 11:25
S26	25	ryf.in.	US-PGPUB; USPAT	OR	ON	2004/01/09 14:09
S27	1	"5618474".pn.	US-PGPUB; USPAT	OR	ON	2004/01/09 14:09

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S28	6221	((coeff\$8 with therm\$6 with expan\$6) or CTE) with silicon	US-PGPUB; USPAT	OR	ON	2004/01/10 17:34
S29	175	((coeff\$8 with therm\$6 with expan\$6) or CTE) with silicon with value	US-PGPUB; USPAT	OR	ON	2004/01/10 17:39
S30	395	((coeff\$8 with therm\$6 with expan\$6) or CTE) with gold	US-PGPUB; USPAT	OR	ON	2004/01/10 17:47
S31	15	((coeff\$8 with therm\$6 with expan\$6) or CTE) same (dielectric\$6 with (layer\$4 or stack\$6) with mirror)	US-PGPUB; USPAT	OR	ON	2004/01/10 18:16
S32	1	"6525880".pn.	US-PGPUB; USPAT	OR	ON	2004/11/29 10:29
S33	1	"6525880".pn. and (mirror same coat\$6)	US-PGPUB; USPAT	OR	ON	2004/01/10 18:13
S34	1558	mirror with coat\$6 with dielectric	US-PGPUB; USPAT	OR	ON	2004/01/10 18:14
S35	144	(mirror with coat\$6 with dielectric) and "385"/\$.ccls.	US-PGPUB; USPAT	OR	ON	2004/01/10 18:14
S36	46	(mirror with coat\$6 with dielectric) and (mirror same (coeff\$8 with therm\$6 with expan\$6))	US-PGPUB; USPAT	OR	ON	2004/01/10 18:17
S37	2488	385/16.ccls. or 385/18.ccls. or 385/47. ccls. or 359/578.ccls.	US-PGPUB; USPAT	OR	ON	2004/01/10 19:10
S38	42	(fabry with perot with cavity) and (radius near2 curvature with (mm or millimeter))	US-PGPUB; USPAT	OR	ON	2004/11/16 13:43
S39	21	(fabry with perot with cavity) and (radius near2 curvature with (mm or millimeter)) and (micrometers or mu)	US-PGPUB; USPAT	OR	ON	2004/11/16 13:40
S40	1	"20030138213"	US-PGPUB; USPAT	OR	ON	2004/11/16 13:43
S41	0	("2003/0138213").URPN.	USPAT	OR	OFF	2004/11/16 13:44
S42	789	(mirror or reflector) with curv\$ with (tilt\$6 or pivot\$6)	US-PGPUB; USPAT	OR	ON	2004/11/16 14:11
S43	364	S42 and ("385"/\$.ccls. or "359"/\$.ccls.	US-PGPUB; USPAT	OR	ON	2004/11/16 14:11
S44	16	S43 and (layer\$6 or substrat\$6) and (dop\$6)	US-PGPUB; USPAT	OR	ON	2004/11/16 14:12
S45	1	"6594059".pn.	US-PGPUB; USPAT	OR	ON	2004/11/29 10:39
S46	1	"20030011864"	US-PGPUB; USPAT	OR .	ON	2004/11/29 11:03
S47	0	sag with curvature with mirror same MEMS	US-PGPUB; USPAT	OR	ON	2004/11/29 11:04
S48	0	sag\$6 with curv\$7 with (mirror\$6 or reflect\$6) same MEMS	US-PGPUB; USPAT	OR	ON	2004/11/29 11:05

S49	6	sag\$6 with curv\$7 with (mirror\$6 or reflect\$6) and MEMS	US-PGPUB; USPAT	OR	ON	2004/11/29 11:09
S50	149	sag\$6 with curv\$7 with (mirror\$6 or reflect\$6)	US-PGPUB; USPAT	OR	ON	2004/11/29 11:09
S51	143	S50 not S49	US-PGPUB; USPAT	OR	ON	2004/11/29 11:09
S52	2	spoil\$6 with sag\$6 with cavity same (mirror\$6 or reflect\$6)	US-PGPUB; USPAT	OR	ON	2004/11/29 11:35
S53	35	(mems with fabry) and ((mirror\$6 or reflect\$6) with (mm or nm or micrometer or millimeter or nanometer))	US-PGPUB; USPAT	OR	ON	2004/11/29 11:58
S54	324	fabry with cavity with length same (mirror\$6 or reflect\$6)	US-PGPUB; USPAT	OR	ON	2004/11/29 11:59
S55	50	fabry with cavity with length same (mirror\$6 or reflect\$6) same (mm or nm or micrometer or millimeter or nanometer)	US-PGPUB; USPAT	OR	ON	2004/11/29 12:00